

Characterization Techniques of Solids

X-ray Diffraction of Solids and Semiconductors

<u>D.J. As</u>,

Universität Paderborn, Department Physik, Warburger Str. 100, 33098 Paderborn, Germany Raum P8.2.10 Tel. 05251 60 5838 E-mail: d.as@uni-paderborn.de



http://physik.uni-paderborn.de/as/

Characterization Techniques of Solids







- Motivation
- Basics of X-ray diffraction
- Laue images
- Powder diffractometry
- Pole figures
- Diffractometry
- High resolution X-ray diffraction
- Glazing Incidence

History





2012 was the 100th Aniversery of X-ray Diffraction

- X-rays were discovered by Wilhelm Conrad Röntgen in 1895
- In 1912, Paul Peter Ewald developed a formula to describe the passage of light waves through an ordered array of scattering atoms, based on the hypothesis that crystals were composed of a space-lattice-like construction of particles.
- Maxwell von Laue realized that X-rays might be the correct wavelength to diffract from the proposed space lattice.
- In June 1912, von Laue published the first diffraction pattern in *Proceedings* of the Royal Bavarian Academy of Science.



The diffraction pattern of copper sulfate, published in 1912



Basics





Characteristic X-ray radiation





- Electrons from the filament strike the target anode, producing characteristic radiation via the photoelectric effect.
- The electrons knock out electrons of an inner shell (K, L; M etc.), electrons of the outer shells drops down under submission of characteristic X-ray emission.
- Fine structure of the atome shell, orbitals split into sublevels $K_{\alpha 1}$, $K_{\alpha 2}$;...
- The anode material (Cu, Mo, Au, ...) determines the wavelengths of characteristic radiation.
- While we would prefer a monochromatic source, the X-ray beam actually consists of several characteristic wavelengths of X rays.





Bragg's law for diffraction



- For parallel planes of atoms, with a space d_{hkl} between the planes, constructive interference only occurs when Bragg's law is satisfied.
 - In our diffractometers, the X-ray wavelength λ is fixed.
 - Consequently, a family of planes produces a diffraction peak only at a specific angle θ.
 - The space between diffracting planes of atoms determines peak positions.
- Additionally, the plane normal [hkl] must be parallel to the diffraction vector s
 - Plane normal [hkl]: the direction perpendicular to a plane of atoms
 - Diffraction vector s: the vector that bisects the angle between the incident and diffracted beam



Structure factor

The diffraction peak intensity is determined by the arrangement of atoms in the entire crystal

$$I_{hkl} \propto |F_{hkl}|^2$$
$$F_{hkl} = \sum_{j=1}^m N_j f_j \exp\left[2\pi i \left(hx_j + ky_j + lz_j\right)\right]$$

- The structure factor F_{hkl} sums the result of scattering from all of the atoms in the unit cell to form a diffraction peak from the (hkl) planes of atoms
- The amplitude of scattered light is determined by:
 - where the atoms are on the atomic planes
 - this is expressed by the fractional coordinates x_i y_i z_i
 - what atoms are on the atomic planes
 - the scattering factor f_j quantifies the efficiency of X-ray scattering at any angle by the group of electrons in each atom
 - The scattering factor is equal to the number of electrons around the atom at 0° $\theta,$ the drops off as θ increases
 - N_j is the fraction of every equivalent position that is occupied by atom j



••••



X-ray beam path and goniometer motions



Figure 2. Illustration of the beam path and the different goniometer motions.

M. Frentrup et al., J. Phys. D: Appl. Phys. 50 (2017) 433002

D.J. As

X-ray equipment



•••••••



Generation of X-rays



- Sealed X-ray tubes tend to operate at 1.8 to 3 kW.
- Rotating anode X-ray tubes produce much more flux because they operate at 9 to 18 kW.
 - A rotating anode spins the anode at 6000 rpm, helping to distribute heat over a larger area and therefore allowing the tube to be run at higher power without melting the target.
- Both sources generate X rays by striking the anode target with an electron beam from a tungsten filament.
 - The target must be water cooled.
 - The target and filament must be contained in a vacuum.
- Exit window: Be





PANalytical X´Pert Pro MPD





---;•



PANalytical X'Pert Pro MPD

Tube and programable slit



Detection side











This image shows a 4-bounce Ge monochromator

- Each pair of diffracting crystals is channel-cut from a single piece of Ge
 - This prevents misorientation between the pair of crystals
- Two sets of channel-cut crystals are used
 - The orientation between these two sets must be precisely aligned to get a usable X-ray beam
- Slits are used to control the width of the beam entering the first channelcut crystal and to control the width in-between the two sets of channelcut crystals





•••••

(a)

(b)



Euler Cradle



Schematic drawing of a diffractometer

FIG. 1. (Color online): Schematic drawing of the diffractometer and the five-movement sample holder.

O. Masson et al., Rev. Sci. Instrum. 76, 063912 (2005)

Characterization Techniques of Solids

Laue measurements



Laue diffraction





A stationary mounted crystal will be irradiated by a white X-ray beam. Since Θ and d are specified by the crystal orientation, one gets a stereografical projection of the (reciprocal) lattice plans at angles 2Θ as points with equal $n\lambda/d$.

$$n\lambda = 2d_{hkl}\sin\Theta_B$$

Bragg condition

The images are taken in transmission (forward scattering) for small crystals or in reflection (backward scattering) on X-ray films, luminescence folie, or X-ray image sensors.

Since the crystal structure (d) is mostly known, Laue images are mainly used to determine the orientation (Θ) of the single crystal (e.g. substrate).





Laue diffraction pattern

- Von Laue's diffraction pattern supported two important hypotheses
 - X-rays were wavelike in nature and therefore were electromagnetic radiation
 - The space lattice of crystals
- Bragg consequently used X-ray diffraction to solve the first crystal structure, which was the structure of NaCl published in June 1913.
- Single crystals produce "spot" patterns similar to that shown to the right.
- However, powder diffraction patterns look quite different.



The second diffraction pattern published was of ZnS. Because this is a higher symmetry material, the pattern was less complicated and easier to analyze



••••



Laue image of wurtzit ALN in c-direction





hcp/Wurzit m (10-10)



Laue image of wurtzit ALN in m-, a-direction and 14° off-oriented

0 0.0 0 0 0 0 ° 90 ah.da c [0001] a [10-10] m [11-20]

D.J. As

a)

hcp/Wurzit a (11-20)



hcp/Wurzit off-orientiert



14° off orientied in relation to the caxes in the direction to the a-axes (and crystal is rotated by 45°)

Determination of the off-orientation x to the plane $x = 1/2 \arctan(L/D)$ L = distance on the film D = distance film – crystal



•••••



Laue images of cubic zincblende structure

fcc/Zinkblende (100)



z 🛉 4-fold



fcc/Zinkblende (110)



fcc/Zinkblende (111)



space group F 43m {100} {111} {110} Powder diffraction





Powder diffraction

An X-ray powder diffraction pattern is a plot of the intensity of X-rays scattered at different angles by a sample



D.J. As

- The detector moves in a circle around the sample
 - The detector position is recorded as the angle 2theta (ω -2 θ)
 - The detector records the number of Xrays observed at each angle 2θ
 - The X-ray intensity is usually recorded as "counts" or as "counts per second"
- Many powder diffractometers use the Bragg-Brentano parafocusing geometry
 - To keep the X-ray beam properly focused, the incident angle omega changes in conjunction with 2theta
 - This can be accomplished by rotating the sample or by rotating the X-ray tube.



••••



Powder diffraction

In an ideal powder all crystal orientations are equally distributed

- Comparision with standard measurements ("PDF-Files")



- Identification of foreign phases (diffraction at angles Θ different to that the main crystal)



••••



Diffractometry of thin layers



Messung d
ünner Schichten mit streifendem Einfall (Grazing Incidence XRD)
 ⇒ Die R
öntgenstrahlen treffen nur Netzebenen in der Oberfl
ächenschicht



Beispiel: In2O3 auf Si(111)-Substrat

Characterization Techniques of Solids

Pole figures



---;•



Texture mapping



Diagram explaining the measurement geometry to map a texture in reciprocal space and its projection onto a 2D map.



•••••



Ni single crystal pole figure



(a) Schematic representation of a Ni single crystal pole figure at d = 2.03 Å.

(b) Reciprocal space representation of the Ni reciprocal lattice and pole figure (red half sphere) in three dimensions.





Preferred Orientation (texture)

- Preferred orientation of crystallites can create a systematic variation in diffraction peak intensities
 - can qualitatively analyze using a 1D diffraction pattern by looking at how observed peak intensities deviate systematically from the ideal
 - a pole figure maps the intensity of a single peak as a function of tilt and rotation of the sample
 - this can be used to quantify the texture



D.J. As





•••••



Pole figures of cubic GaN on 3C-SiC



Pole figures for different wurtzite and zincblende reflections of GaN grown on (0 0 1) *zb* oriented 3C-SiC/Si-templates (a)–(c). The diagram illustrates the crystallographic arrangement of both phases.

D.J. As

Characterization Techniques of Solids

High resolution XRD







HRXRD and XRR are both used to study thin films and benefit from the same optics, so we often consider them together

HRXRD can measure:

- Structural Information
 - Composition
 - Thickness
 - Superlattice period
- Defects
 - Mismatch
 - Relaxation
 - Misorientation
 - Dislocation Density
 - Mosaic Spread
 - Curvature
 - Inhomogeneity
 - Surface Damage

XRR can measure:

- Thickness
- Surface and Interface Roughness
- Density or composition of the topmost layer



Various scan types

Table 2. Scan types available on high-resolution diffractometers. ω refers to the angle between the incident beam and the sample surface, 2θ refers to the angle between the incident and diffracted beams.

Scan type	Description
2θ-ω	The sample (or the x-ray source) is rotated by ω and the detector is rotated by 2θ with an angular ratio of 1:2. In reciprocal space, <i>S</i> moves outwards from the origin. The <i>length</i> of <i>S</i> changes, but its <i>direction</i> remains the same and depends on the offset. For $2\theta - \omega$ scans, the x-axis is in units of 2θ , whereas for $\omega - 2\theta$ scans, the x-axis is in units of ω . When there is no offset and $\omega = \theta$ this is a symmetrical scan ($\theta - 2\theta$) which is vertical in reciprocal space. Standard scan type for powder diffraction
$\omega - 2\theta$	Simply a $2\theta - \omega$ scan, but with ω on the x-axis. Standard scan type for reflectivity and high-resolution work.
20	The sample and source remain stationary and the detector is moved. S traces an arc along the circumference of the Ewald sphere. Both the <i>length</i> and the <i>direction</i> of S change.
ω-scan	The detector remains stationary and the sample is rotated about the ω axis. In reciprocal space, S traces an arc centred on the origin. The <i>length</i> of S stays the same, but its <i>direction</i> changes.
Q-scan	Software can be used to scan ω and 2θ in non-integer ratios, scanning S along a given direction in reciprocal space. Reciprocal space maps of any desired shape (in reciprocal space) can then be collected ^a .
ϕ	Rotation of the sample about the ϕ axis (usually in the plane of the sample). The <i>length</i> of S stays the same, but the sample is moved, bringing the reciprocal lattice spot through S so that the <i>direction</i> of S changes with respect to the sample.
χ	Similar to ϕ scans, except that the sample is rotated about the χ axis (plane of the sample rotated with respect to the incoming beam).

M A Moram and M E Vickers Rep. Prog. Phys. 72 (2009) 036502



••••



Schematic plot of the of the Philips X'pert material research diffractometer consisting of the X-ray tube, hybrid monochromator, euler cradle and detector.







Reciprocal space





-



Scattering vectors Q







Scattering vector Q: $Q_{\perp} = Q_{z} = \frac{2\pi}{a_{\perp}} = \frac{2\pi}{\lambda} \left[\cos(\theta - \omega) - \cos(\theta + \omega) \right]$ $Q_{\Box} = Q_{x} = \frac{2\pi}{a_{\Box}} = \frac{2\pi}{\lambda} \left[\sin(\theta - \omega) + \sin(\theta + \omega) \right]$ $\frac{1}{d} = \sqrt{Q_{x}^{2} + Q_{z}^{2}} = \sqrt{Q_{\Box}^{2} + Q_{\bot}^{2}}$

29

ω -2 Θ scans





📑 🛛 SiGe on Si



A typical diffraction spectrum of a symmetric "single scans" of an SiGe-epilayer on Si.





HRXRD of Si/SiGe superlattice deposited on (001) Si



Fig. 6.44. HRXRD of Si/SiGe superlattice deposited on (001) oriented Si. SL period D = 227 Å with 10 double layers corresponding to a total thickness of 2270 Å. The number of secondary maxima in-between the main SL satellite peaks is 10-2=8

D.J. As

Characterization Techniques of Solids





$(002) \omega - 2\theta$ scan from MQWs



Rocking curve (ω-scan)





Rocking curve

A rocking curve (a-scan) produces observed intensity from planes that are not perfectly parallel



- In a rocking curve, the detector is set at a specific Bragg angle and the sample is tilted.
- A perfect crystal will produce a very sharp peak, observed only when the crystal is properly tilted so that the crystallographic direction is parallel to the diffraction vector s
 - The RC from a perfect crystal will have some width due to instrument broadening and the intrensic width of the crystal material
- Defects like mosaicity, dislocations, and curvature create disruptions in the perfect parallelism of atomic planes
 - This is observed as broadening of the rocking curve
 - The center of the rocking curve is determined by the dspacing of the peaks



Characterization Techniques of Solids

D.J. As



••••



Linewidth dependence of cubic GaN epilayers vs film thickness



Decrease of the XRD ω -linewidth (FWHM) with increasing film thickness for oriented zincblende GaN grown on relevant substrates 3C-SiC, GaAs, MgO, and Si.



Reduction in the defect density and an improvement in the material quality for thicker epitaxial films

M. Frentrup et al., J. Phys. D: Appl. Phys. 50 (2017) 433002

D.J. As

Characterization Techniques of Solids





Bowing of 3C-SiC wafer



M. Frentrup et al., J. Phys. D: Appl. Phys. 50 (2017) 433002

D.J. As

Characterization Techniques of Solids

Reciprocal Space Mapping (RSM)





Reciprocal space Map







RSM of cubic GaN with and without hexagonal Inclusions







k-space map

••••





D.J. As

Glazing incident XRD (GIXRD) X-ray Reflection (XRR)





Diffractometry of thin layers

Investigations of thin films with grazing incidence XRD

X-rays hit the lattice planes at the surface layer



Schematic diagram of grazingincidence x-ray diffraction (GID). θ Bragg angle, ϕ angle of incidence, ϕ' exit angle of diffracted beam, ω angle of rotation around surface normal (azimuth).

Angle of incidence typically < 4°, but larger than angle of total reflection X-ray will be absorbed in the surface layer.

Angle smaller than angle of total reflection

diffraction of the evanescente wave (only a few surface monolayers)





X-ray reflection



D.J. As

Characterization Techniques of Solids

40





What techniques can be used to get which film information

	Thickness	Composition	Lattice Strain/ Relaxation	Defects	Orientation	Residual Stress	Crystallite Size
Perfect Epitaxy	XRR, HRXRD	HRXRD, RC	Assume 100%	Assume none	HRXRD		
Nearly perfect epitaxy	XRR, HRXRD	HRXRD, RC	HRXRD	RC	HRXRD		
Textured epitaxial*	XRR, HRXRD	HRXRD	HRXRD, IP- GIXD	RC	HRXRD		
Strongly textured polycrystalline	XRR	XRPD, IP- GIXD	IP-GIXD	XRPD, IP-GIXD	IP-GIXD, PF	IP-GIXD	XRPD, IP- GIXD
Textured polycrystalline	XRR	XRPD, GIXD or IP- GIXD		XRPD, GIXD OR IP-GIXD	PF	Psi	XRPD, GIXD
Polycrystalline	XRR	XRPD, GIXD		XRPD, GIXD	PF	Psi	XRPD, GIXD
Amorphous	XRR						

XRR- X-Ray Reflectivity **HRXRD-** High Resolution XRD using coupled scan or RSM **RC-** Rocking Curve **XRPD-** Bragg-Brentano powder diffraction **GIXD-** grazing incidence XRD **IP-GIXD-** in-plane grazing incidence XRD **PF-** pole figure **Psi-** sin²psi using parellel beam





References

- P. Kidd , XRD of gallium nitride and related compounds: Strain, composition and layer thickness, PANalytical ISBN 978-90-809086-7-3
- M. Frentrup et al., J. Phys. D: Appl. Phys. 50, 433002(2017)
- O. Masson et al., Rev. Sci. Instrum. 76, 063912 (2005)
- S.A. Speakman, Basics of X-ray Powder Diffraction, MIT Center for Materials Science and Enginiering USA <u>http://prism.mit.edu/xray</u>
- S.A. Speakman, Introduction to High Resolution X-Ray Diffraction of Epitaxial Thin films, MIT Center for Materials Science and Enginiering, USA <u>http://prism.mit.edu/xray</u>
- M. Birkholz *Thin Film Analysis by X-ray Scattering*, Wiley-VCH (2006)
- P.F. Fewster X-ray Scattering from Semiconductors, Imperial College Press (2000)
- U. Pietsch, V. Holy, T. Baumbach, *High-Resolution X-ray Scattering from Thin Films to Lateral Nanostructures*, Springer (2004)

Thank you for your attention